

Sheet 1 of 1

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				ATTY. DOCKET NO.	SERIAL NO.		
				M125-0428	10005.001		
				APPLICANT: Terry L. Gilan		10/1695961	
				FILING DATE: October 27, 2003	GROUP: Unknown 2815		
U.S. PATENT DOCUMENTS							
Examiner's Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
MC	AA	6,238,974 B1	05/01	Chem et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AM						
	AN						
	AO						
	AP						
	AQ						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)							
	AR						
	AS						
	AT						
EXAMINER	DATE CONSIDERED <i>Matthew C. Julian</i> 10/27/04						
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Best Available Copy

Form PTO-1449				U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M123-2428	PRIORITY SERIAL NO. 10/695961 10/27/2003
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT T. L. Gilton		PRIORITY FILING DATE June 21, 2003	
						PRIORITY GROUP 3410 2815	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
MCL	AA	6,187,604 B1	2/13/01	Gilton			
	AB						
	AC						
	AD						
	AE						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
	AM						Yes
	AN						No
	AO						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)							
MCL	AR	Anodic Oxidation of Porous Silicon Layers Formed on Lightly p-Doped Substrates: A. Baisay et al; pp. 3450-3456; J. Electrochem. Soc. Vol 138, No. 11; November 1991; The Electrochemical Society, Inc.					
MCL	AS	Information and Properties of Porous Silicon Film; Yoshinobu Arita and Yoshio Suda: Journal of the Electrochemical Society; Vol. 124, No. 2; February 1977; pp. 285-295					
MCL		Building from the Bottom Up; Nano Technology; October 16, 2000; C & EN pg. 27-32					
MCL		New Tools for Tiny Jobs; Nano Technology; October 16, 2000; C & EN pg. 33-35					
MCL		Firms Find a New Field of Dreams; Nano Technology; October 16, 2000; C & EN pg. 36-38					
MCL	AT	Crafting a National Nanotechnology Effort; Nano Technology; October 16, 2000; C & EN pg. 39-42					
EXAMINER <i>Michael J. Lur</i>		DATE CONSIDERED 10/27/2004					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							